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José Sasián
Richard N. Youngworth
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Introduction

We never cease to be grateful to the wonderful community that makes this niche specialty conference so memorable. This year, the eighth in the conference series, was certainly no exception to this sentiment. The 2014 Optical System Alignment, Tolerancing, and Verification VIII conference in San Diego was once again excellent. As usual our conference consisted of a day of quality presentations, poster session, and subsequent proceedings articles. We had four sessions involving optical design and tolerance analysis, verification, and alignment of optical systems. We sincerely thank our invited speakers, contributed speakers, poster paper presenters, and the superb community for our success in this conference. The community clearly values this conference and the exchange of ideas it creates.

We must of course thank our program committee for continuing to promote this conference. Finally we thank the volunteers and SPIE staff for providing us the opportunity to cover the subjects of optical system alignment, tolerancing, and verification in a dedicated conference and proceedings volume.

This conference will continue in 2015, which is the International Year of Light. We encourage everyone interested in optical system alignment, tolerancing, and verification to look for the call for papers and to submit your work in early 2015. Please feel free to contact us or anyone on our program committee if you have any questions.

In the meantime, we wish you all the best in your endeavors.

José Sasián
Richard N. Youngworth